

An Improved Piezoelectric Valveless Impedance Micropump

黃偉瑞、鄭江河

E-mail: 9806443@mail.dyu.edu.tw

ABSTRACT

This paper presents the fabrication and Improved experimental studies of flow performance on a valveless micro impedance pump. Piezoelectric valveless impedance micropump is the use of piezoelectric actuators in an asymmetric center to impose a fixed frequency of extrusion. A pressure head can be built up to drive flow through the accumulative effects of wave propagation and reflection originating from the periodic PZT excitation, located asymmetrically along the length of the compressible section of the channel. The micro impedance pump was constructed of three nickel electroforming components, two glass tubes, a PZT actuator and a glass substrate. The main different is the width of the flow channel, the flow of different materials on the bottom of whether it will affect the flow and use of finite element analysis software for this whole piezoelectric actuator design modules of all sizes for analysis.

Focus on a variety of experimental conditions, the driving voltage, driving frequency of the micro pump effect of flow rate, find out the maximum flow, experimental results show that voltage pump 200Vpp, the frequency of 18.3kHz sine wave drive, the maximum flow can be per minute up to 0.24 ml.

Keywords : PZT actuator、electroforming、ANSYS、micro impedance pump、valveless

Table of Contents

封面內頁

簽名頁

授權書 iii

中文摘要 iv

英文摘要 v

致謝 vi

目錄 vii

圖目錄 ix

表目錄 xii

第一章 緒論

1.1前言 1

1.2研究動機 2

1.3文獻回顧 3

第二章 改良式阻抗型微幫浦之設計

2.1壓電式阻抗型無閥微幫浦概念 9

2.2阻抗型幫浦的作動 9

2.3改良式壓電式阻抗型無閥微幫浦 10

第三章 ANSYS有限元素結構分析

3.1改良式壓電式阻抗型無閥微幫浦結構元件分析 16

3.2艙體有水之最佳尺寸分析 19

第四章 幫浦結構元件製作

4.1黃光製程 22

4.2電鑄製程 24

4.3結構元件製作 27

4.4壓電致動器之製作 31

4.5阻抗型無閥微幫浦之組裝 32

第五章 組裝及實驗量測

5.1實驗量測設備與架設說明 35

5.2壓電微幫浦測試	37
5.2.1底層材質不同之測試	39
5.2.2流道寬度不同之測試	41
5.2.3背壓對微幫浦流率的影響	42
第六章 結論	
6.1結論	46
參考文獻	47

REFERENCES

- [1] H. T. C. Van Lintel, "A Piezoelectric Micropump Based on Micro-machining of Silicon," Sensors and Actuator, Vol. 15, pp. 153-167, 1988.
- [2] Olsson, G. Stemme and E. Stemme, "A Valve-less Diffuser / Nozzle Based Fluid Pump," Sensors and Actuators, Vol. 39, pp. 159-167, 1993.
- [3] Gerlach, T., Schuenemann, M. & Wurmus, H., "A new micropump principle of the reciprocating type using pyramidal microfluidic channels as passive valves", Journal of Micromechanics and Microengineering, vol. 5, pp. 199-201, 1995.
- [4] Olsson, G. Stemme and E. Stemme, "A Valve-less Planar Fluid Pump Chambers," Sensors and Actuators, Vol. 46, pp. 549-556, 1995.
- [5] Olsson, G. Stemme and E. Stemme, "Diffuser-element Design Investigation for Valve-less Pumps," Sensors and Actuators, Vol. 57, pp. 688-695, 1996.
- [6] Khoo, M. & Lin, C., "A novel Micromachined Magnetic Membrane Microfluid Pump," Proceeding of the 22nd Annual EMBS International Conference, July 23, pp. 2394-2397, 2000.
- [7] Andersson, H., van der Wijngaart, W., Nilsson, P., Enoksson, P. & Stemme, G., "A valve-less diffuser micropump for microfluidic analytical systems," Sensors and Actuators B, vol. 72, pp. 259-265, 2001.
- [8] Tsai, J. & Lin, L., "A Thermal-Bubble-Actuated Micro-nozzle-Diffuser Pump," Journal of Microelectromechanical Systems, vol. 11, pp. 665-671, 2002.
- [9] D. Rinderknecht & A.I. Hickerson, "A valveless micro impedance pump driven by electromagnetic Actuation," JMM, vol. 15, pp. 861-866, 2005.
- [10]簡嘉男， “壓電式阻抗型無閥微幫浦”，大葉大學機械工程研究所95碩士班論文。
- [11]A. I. Hickerson, D. Rinderknecht, & M. Gharib, "Experimental Study of the Behavior of A Valveless Impedance Pump", Experiments in Fluids, 2005.